

Amendments to the Specification:

Please replace the paragraph beginning at page 5, line 13, with the following amended paragraph:

The in-situ monitor 40 includes a sensor 150 and a drive and sense circuitry 160 in a recess 26 of the rotating platen 24. The sensor 150 detects eddy currents in one or more metal layers of the substrate 10. A suitable in-situ monitor is disclosed in U.S. Patent Application Serial No. 09/574,008, filed May 19, 2000, U.S. Patent Application Serial No. 09/847,867, filed May 2, 2001, and U.S. Patent Application Serial No. 10/633,276, filed July 31, 2003, the entire disclosures of which are incorporated herein by reference. The in situ monitor 40 can include an optical sensor 140 mounted in the recess 26 in addition to (or instead of) the eddy current sensor 150. The optical sensor 140 can include a light source 144 to generate a light beam 142, and a detector 146 to detect reflections of the light beam from the substrate, as discussed in U.S. Patent Application Serial No. 09/847,867.